



[SD2] Plasma Sources and Technologies V

Date / Time	July 28 (Sat.), 2018 / 10:50-12:30
Place	Room D (#115)
Session Chair(s)	Hyo-Chang Lee (KRISS, Korea)

SD2-1

10:50-11:10

The Effects of Asymmetric Secondary Electron Emission Induced by Different Materials Electrodes in Capacitively Coupled Plasmas

Jing-Yu Sun, De-Qi Wen, Yong-Xin Liu, and You-Nian Wang
Dalian Univ. of Tech., China

SD2-2

11:10-11:30

Numerical Study on Tempo-Spatially Varying Thermofluid Field in Tandem Type of Modulated Induction Thermal Plasmas-Effect of Lower Coil Current Modulation

Kazuki Onda¹, Kotaro Shimizu¹, Yasunori Tanaka¹, Yoshihiko Uesugi¹, Tatsuo Ishijima¹, Shiori Sueyasu², Shu Watanabe², and Keitaro Nakamura²
¹*Kanazawa Univ., Japan*, ²*Nisshin Seifun Group Inc., Japan*

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11:30-11:50

Investigations of Argon Arc Attachment Modes on the Anode: The Effect of Gas Temperature

Su-Rong Sun and Hai-Xing Wang
Beihang Univ., China

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11:50-12:10

Voltage Balancing of External Antenna for Inductively Coupled Plasma for Mixture of Oxygen, Nitrogen, Hydrogen, Ammonia, and Forming Gas

Jong Woo Park, Sang Moon Yoo, Hyo Jeong Seo, Aram Kim, and Sung Jin Yoon
PSK Inc., Korea

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12:10-12:30

Withdrawn